



Att'y. Dkt. No. AMAT/5262/CMP/CMP/RKK

**where Application of:**

Tsai, et al.

**Serial No.: 09/961,134**

Confirmation No.: 4110

**Filed: September 21, 2001**

**For: Method and Apparatus For Forming Metal Layers**

**Group Art Unit: 1753**

**Examiner:** Wong, Edna

**MAIL STOP AF**  
**Commissioner for Patents**  
**P.O. Box 1450**  
**Alexandria, VA 22313-1450**

# CERTIFICATE OF MAILING

37 CFR 1.8

I hereby certify that this correspondence is being deposited on April 20, 2004, with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

4/20/04

Date \_\_\_\_\_

Keith M. Zander

**Dear Sir:**

**RESPONSE TO FINAL OFFICE ACTION DATED FEBRUARY 6, 2004**

In response to the Final Office Action dated February 6, 2004, having a shortened statutory period for response set to expire on May 6, 2004, please enter this response and reconsider the claims pending in the application for reasons discussed below. Although Applicant believes that no additional fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/AMAT/5262/KMT, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

**Amendments to the Specification** begin on page 2 of this paper. **Amendments to the Claims** are reflected in the listing of claims which begins on page 4 of this paper. **Remarks** begin on page 5 of this paper.